

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Masahiko NAKAMORI, et al.  
App. No : 10/536621  
Filed : May 26th, 2005  
For : POLISHING PAD AND METHOD OF  
PRODUCING SEMICONDUCTOR  
DEVICE  
Examiner : Sylvia R. MacArthur  
Art Unit : 1792  
Conf # : 9275

**AMENDMENT AFTER FINAL****Mail Stop AF**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed June 2<sup>nd</sup>, 2008, please reconsider the present application in light of the following amendments and comments.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.